

## BENCHTOP PLASMA SYSTEM

# PE-75

24"

18"



THE PLASMA ETCH, INC. PE-75 IS OUR LARGEST ENTRY LEVEL PLASMA SYSTEM AND OFFERS MANY FEATURES NOT FOUND IN COMPETITIVE UNITS.

THIS SYSTEM FEATURES A CIRCULAR ALUMINUM VACUUM CHAMBER THAT IS 12" IN DIAMETER AND 11" DEEP WITH A DIRECT POWERED RF ELECTRODE. AS IN ALL PLASMA ETCH SYSTEMS, A CAPACITIVE PARALLEL PLATE DESIGN IS USED FOR THE MOST EFFECTIVE PLASMA GENERATION.

THE PE-75 FEATURES A PLC MICROPROCESSOR CONTROL SYSTEM, AND A KEYPAD USER INTERFACE WITH ALPHA-NUMERIC DISPLAY. A SINGLE PROCESS RECIPE FOR AUTOMATIC PROCESS SEQUENCING CAN BE STORED.

THE COMPACT SIZE AND AFFORDABILITY OF THE PE-75 MAKES THIS SYSTEM PERFECT FOR SMALLER PRODUCTION FACILITIES, R&D FACILITIES, AND UNIVERSITIES.

THE PE-75 IS COMPRISED OF

COMPONENTS MADE IN THE USA AND IS BUILT IN AND SUPPORTED FROM OUR CARSON CITY, NV HEADQUARTERS WITH SOME OF THE BEST CUSTOMER SERVICE AVAILABLE IN THE INDUSTRY.

**PLASMA ETCH**  
PROGRESS THROUGH INNOVATION

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## STANDARD SYSTEM FEATURES

DURABLE ALUMINUM VACUUM CHAMBER  
APPROXIMATE INSIDE DIMENSIONS; 12" DIAMETER X 11' DEEP  
SINGLE 9W" X 10D" HORIZONTAL "DIRECT CONTACT" RF POWERED ELECTRODE  
5.5" (MINIMUM) CHAMBER HEIGHT CLEARANCE  
400 WATT, 50 KHZ CONTINUOUSLY VARIABLE RF POWER SUPPLY  
2 ROTOMETERS, 2 GAS CONTROLS, 0-25CC/MIN W/PRECISION NEEDLE VALVES  
THERMOCOUPLE VACUUM GAUGE, 0-1 TORR  
PLC MICROPROCESSOR CONTROL SYSTEM  
CONSOLE DIMENSIONS: 18"W X 19"D X 24"H  
5 CFM 2-STAGE DIRECT DRIVE OIL VACUUM PUMP

## OPTIONAL SYSTEM FEATURES

100W 13.56 MHZ RF POWER SUPPLY WITH AUTOMATIC RF MATCHING NETWORK.

## SYSTEM ELECTRICAL & MECHANICAL

PLASMA CONSOLE 18" X 19" X 24" / 90LBS  
VACUUM PUMP 38LBS  
ELECTRICAL; 120VAC, 15A

CONTACT US TODAY  
FOR A QUOTE ON YOUR CUSTOM  
PLASMA MACHINE

775.883.1336

WWW.PLASMAETCH.COM

3522 ARROWHEAD DRIVE CARSON CITY NV. 89706

